

Contents

<i>Acknowledgments</i>	<i>page</i> xii
<i>List of Abbreviations</i>	xiii

1	An Introduction to Radio Frequency Nanoelectronics	1
1.1	Radio Frequency Nanoelectronics	1
1.2	Measurement Problems in RF Nanoelectronics	4
1.3	Measurement Techniques for RF Nanoelectronics	5
References		8
2	Core Concepts of Microwave and RF Measurements	11
2.1	Introduction	11
2.2	Maxwell's Equations	11
2.2.1	Macroscopic Equations	11
2.2.2	Vector and Scalar Potentials	12
2.2.3	Hertz Vector Potentials	14
2.2.4	Transition from Fields to Transmission Lines	16
2.3	Transmission Line Theory	18
2.4	Impedance, Admittance, and Scattering Matrixes	22
2.5	Signal Flow Graphs	25
2.6	Device De-embedding and Calibration	27
2.6.1	De-embedding	27
2.6.2	Multiline TRL and Other Calibration Techniques	28
2.6.3	On-Wafer Calibration	31
2.7	Multimode Calibration	31
2.8	Calibration of a Scanning Microwave Microscope and Other One-Port Systems	33
References		34
3	Extreme Impedance Measurements	36
3.1	The Impedance Matching Challenge in RF Nanoelectronics	36
3.2	An Introduction to Extreme Impedance Measurements	37

3.3	Impedance Matching Networks	40
3.4	Reflectometer Methods for One-Port Devices	42
3.4.1	Implementation with a Power Splitter	42
3.4.2	Implementation with a Hybrid Coupler	43
3.5	Statistical Measurements	45
3.5.1	Use of Redundant Measurements in the Reflectometer Method	45
3.5.2	Use of Redundant Measurements to Characterize a Power Splitter	46
3.6	Interferometer with Active Signal Injection	48
	References	50
4	On-Wafer Measurements of RF Nanoelectronic Devices	52
4.1	Broadband Characterization of RF Nanoelectronic Devices	52
4.2	Practical Considerations for On-Wafer Measurements	53
4.3	Wheatstone Bridge Approach	57
4.3.1	The Wheatstone Bridge	57
4.3.2	Bridge-Based Measurements of a Nanoelectronic Device	58
4.4	Empty Device Approach	61
4.5	Fabrication of Impedance-Matched On-Wafer Devices	64
	References	65
5	Modeling and Validation of RF Nanoelectronic Devices	67
5.1	Introduction	67
5.2	Modeling and Validation of Measurement Methods	68
5.2.1	Electromagnetic Properties of Nanoscale Conductors	68
5.2.2	An Overview of Validation	70
5.2.3	Validation with Finite-Element Models	71
5.2.4	Validation with Circuit Models	74
5.3	Extracting Circuit Parameters from Measurements	75
5.3.1	Nanowire Device Parameters	75
5.3.2	Full-Wave, Finite-Element Approach	76
5.3.3	Transmission Line Approach	77
5.3.4	Lumped Element Approach	80
5.3.5	Modeling and Parameter Extraction for CNT Devices	83
5.3.6	Iterative Optimization Approach	85
	References	87
6	Characterization of Nanofiber Devices	90
6.1	The Measurement Problem	90
6.2	Device Geometry and Fabrication	91
6.3	Calibrated On-Wafer Measurements	93
6.4	Uncertainty Analysis	97
6.5	Extraction of Parameters from Circuit Models	100
	References	102

Contents

ix

7	Instrumentation for Near-Field Scanning Microwave Microscopy	104
7.1	Introduction	104
7.2	Historical Development	104
7.3	Probe and Sample Motion	106
7.3.1	Distance-Following Mechanisms	106
7.3.2	Probe and Sample Positioning	111
7.4	Microwave Probes and Circuits	111
7.4.1	Aperture Probes versus Tip Probes	111
7.4.2	Resonant Probes versus Nonresonant Probes	114
7.5	Other Aspects of Near-Field Scanning Microwave Microscope Instrumentation	118
	References	120
8	Probe-Based Measurement Systems	123
8.1	An Overview of Probe-Based Measurement Systems	123
8.2	Simple Tip-Sample Models	124
8.2.1	General Considerations	124
8.2.2	Coupling Capacitance: Parallel Plate Model	125
8.2.3	Coupling Capacitance: Spherical and Conical Tip Shapes	126
8.2.4	Coupling Capacitance: Elementary Antenna Approach	128
8.3	Calibration Procedures for Microwave Scanning Probe Microscopes	130
8.3.1	Calibration of Near-Field Scanning Microwave Microscopes Operating in Reflection Mode	130
8.3.2	Calibration of an Interferometric Scanning Microwave Microscope	138
8.3.3	Time-Domain Approaches in Scanning Microwave Microscopy	141
8.3.4	Calibration of Evanescent Microwave Magnetic Probes	143
8.3.5	Evanescent Microwave Microscopes in Transmission Mode	144
	References	145
9	Radio Frequency Scanning Probe Measurements of Materials	149
9.1	Electromagnetic Characterization of Materials: Fundamental Concepts	149
9.2	Impedance Circuit Models of Probe–Sample Interactions	153
9.2.1	Toward Materials Characterization with Near-Field Scanning Microwave Microscopy	153
9.2.2	Near-Field, Lumped-Element Models	153
9.2.3	Transmission Line Models	156
9.3	Resonant Cavity Models and Methods	158
9.3.1	Resonant-Cavity-Based, Near-Field Scanning Microwave Microscopy	158
9.3.2	Resonant Cavity Measurements with Swept Frequency	159
9.3.3	Calibration, Uncertainty, and Sensitivity	163
9.3.4	Resonant Cavity Measurements of Semiconductors	165
9.3.5	Nonlinear Dielectric Microscopy of Materials	171

9.4	Measurements of Thin Films and Low-Dimensional Materials	173
9.4.1	Materials for RF Nanoelectronics	173
9.4.2	Dielectric Film Characterization	173
9.4.3	Measurements of Graphene	174
9.4.4	Measurements of Transition Metal Dichalcogenides	179
	References	182
10	Measurement of Active Nanoelectronic Devices	187
10.1	Applications of RF Nanoelectronics	187
10.2	Modeling and Measurement of Active Devices	189
10.2.1	Small-Signal Models of Conventional Transistors	189
10.2.2	Microwave Measurements of Conventional Transistors	190
10.3	Determination of Equivalent Circuit Parameters for a Nanotransistor	192
	References	201
11	Dopant Profiling in Semiconductor Nanoelectronics	203
11.1	Introduction	203
11.2	Tip-Sample Models for Semiconductor Samples	204
11.2.1	Capacitive Models	204
11.2.2	Metal-Semiconductor Models	206
11.2.3	Metal-Oxide-Semiconductor Model	207
11.3	Dopant Profiling with Scanning Capacitance Microscopy	210
11.4	Dopant Profiling with Near-Field Scanning Microwave Microscopy	213
11.5	Dopant Characterization with Other Microscopy Techniques	218
	References	219
12	Depth Profiling	222
12.1	Introduction to Nanoscale Depth Profiling	222
12.2	Theoretical Foundation of Depth Profiling	223
12.2.1	Near-Fields and Tomography	223
12.2.2	Near-Field of an Elementary Dipole	224
12.2.3	Near-Field Scattering at a Sub-wavelength Aperture	225
12.2.4	Solution to the Forward Problem	227
12.2.5	Solution to the Inverse Problem	230
12.2.6	Linear Inverse Problem Solutions from Frequency Shift Measurements	231
12.2.7	Inverse Problem Solutions from Multifrequency or Multipoint Scattering Field Data	233
12.2.8	Inverse Problem Solutions from Multifrequency Scattering Field Data	235
12.2.9	Inverse Problem Solutions from Multifrequency or Multipoint Scattering Reflection Coefficient Data	241

Contents

xi

12.3	Experimental Subsurface Tomography with Near-Field Microwave Microscopes	242
	References	248
13	Dynamics of Nanoscale Magnetic Systems	251
13.1	Introduction to Magnetization Dynamics	251
13.2	Measurements of Linear Dynamics in Microscale and Nanoscale Magnetic Systems	255
13.2.1	Mechanical Measurement of Magnetization Dynamics	255
13.2.2	Time- and Frequency-Domain Measurements of Magnetization Dynamics	262
13.2.3	Measurements of Magnetization Dynamics in Layered Structures	264
13.3	Scanning Probe Measurements of Magnetization Dynamics	269
	References	274
14	Nanoscale Electromagnetic Measurements for Life Science Applications	279
14.1	High-Resolution Optical Microscopy of Nanoscale Biological Systems	279
14.1.1	Far-Field Techniques	279
14.1.2	Near-Field Techniques	281
14.2	Electrical Characterization of Biological Systems	282
14.2.1	The Measurement Problem	282
14.2.2	Microwave Antenna Probes	282
14.2.3	Multilayer Systems	287
14.2.4	Heterogeneous, Liquid Systems	290
14.3	Electrical Scanning Probe Microscopy of Biological Systems	293
14.3.1	General Considerations	293
14.3.2	Electrostatic Force Microscopy	293
14.3.3	Near-Field Scanning Microwave Microscopy of Biological Systems	296
14.3.4	Topographic Artifacts in Microwave Microscopy	296
14.3.5	Scanning Probe Microscopy at the Cellular Level	301
	References	304
	<i>Index</i>	307